

Title (en)

SURFACE IONISATION-TYPE ION SOURCE, PARTICULARLY FOR THE REALISATION OF AN IONIC PROBE

Publication

EP 0165140 B1 19880518 (FR)

Application

EP 85400969 A 19850515

Priority

FR 8407606 A 19840516

Abstract (en)

[origin: US4801849A] An ion source is described, including a source of neutral particles which arrive at an ionization support positioned inside a chamber which is closed by a cap and which includes lateral walls. The cap includes an outlet orifice opposite which a plate defines a main ionization active surface. An electric field is applied between said device and by an electrode placed downstream from the orifice in the direction of ion emission and fitted with a corresponding opening. Overall, the ionization support defines, by virtue of its active surface, and by virtue of holes surrounding said central active surface, a baffle assembly which prevents neutral atoms from passing directly to the outlet orifice, and which contributes to a high degree of ionization.

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H01J 27/26

IPC 8 full level

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